

Notice of References Cited	Application/Control No. 10/805,871		Applicant(s)/Patent Under Reexamination KIM ET AL.	
	Examiner Natasha Young		Art Unit 1797	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,251,658 B1	06-2001	Henderson et al.	435/285.1
*	B	US-2003/0180965 A1	09-2003	Yobas et al.	436/180
*	C	US-6,590,139 B1	07-2003	Lee et al.	800/24
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Machine translation of JP 11-347971 A. The Japanese Patent was provided in the IDS and has a date of 12/21/1999.
	V	Fung et al, A 2-D PVDF Force Sensing System for Micro-manipulation and Micro-assembly, May 2002, IEEE, 1489-1494.
	W	Fung et al, Internet-Based Remote Sensing and Manipulation in Micro Environment, July 2001, IEEE, 695-700.
	X	DeVoe et al, Modeling and Optimal Design of Piezoelectric Cantilever Microactuators, Journal of Microelectromechanical Systems, Vol. 6, No. 3, September 1997, 266-270.

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.